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CLAIMS:

- A surface acoustic wave sensor assembly comprising:

 a surface acoustic wave sensor comprising a plurality of electrodes;
 a circuit layer including an aperture and a plurality of electrical contacts; and
 a Z-axis conductive layer to couple the electrical contacts to the electrodes.
 - 2. The surface acoustic wave sensor assembly of claim 1, wherein the Z-axis conductive layer comprises a Z-axis conductive elastomer.
 - 3. The surface acoustic wave sensor assembly of claim 2, wherein the Z-axis conductive elastomer forms a hermetic barrier between the surface acoustic wave sensor and the circuit layer.
- 4. The surface acoustic wave sensor assembly of claim 1, wherein the surface acoustic wave sensor forms part of a sensor cartridge and the surface acoustic wave sensor is exposed to a fluid path within the cartridge via the aperture.
- 5. The surface acoustic wave sensor assembly of claim 1, wherein the surface acoustic wave sensor comprises a Love mode shear-horizontal surface acoustic wave sensor.
 - 6. The surface acoustic wave sensor assembly of claim 1, wherein the electrical contacts of the circuit layer comprise circuit traces formed on the circuit layer.
 - 7. The surface acoustic wave sensor assembly of claim 1, wherein the electrodes are located at a periphery of the sensor.
 - 8. A sensor cartridge comprising:a housing comprising a fluid path; and
 - a surface acoustic wave sensor assembly comprising a surface acoustic wave sensor that comprises a plurality of electrodes, a circuit layer that comprises an aperture

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and a plurality of electrical contacts, and a Z-axis conductive layer to couple the electrical contacts to the electrodes, wherein the surface acoustic wave sensor is exposed to the fluid path via the aperture.

- 5 9. The sensor cartridge of claim 8, wherein the plurality of electrical contacts are not exposed to the fluid path.
 - 10. The sensor cartridge of claim 8, wherein the Z-axis conductive layer comprises a Z-axis conductive elastomer.
 - 11. The sensor cartridge of claim 10, wherein the Z-axis conductive elastomer forms a hermetic barrier between the surface acoustic wave sensor and the circuit layer.
- The sensor cartridge of claim 8, wherein the surface acoustic wave sensor
 comprises a Love mode shear-horizontal surface acoustic wave sensor.
 - 13. The sensor cartridge of claim 8, wherein the housing comprises an input port to the fluid path.
- 20 14. The sensor cartridge of claim 13, wherein the fluid path comprises an input reservoir proximate the input port, an output reservoir, and a channel between the input reservoir and output reservoir, wherein the aperture is proximate the channel.
 - 15. The sensor cartridge of claim 14, further comprising sorbent material inside the output reservoir.
 - 16. The sensor cartridge of claim 15, wherein the housing comprises an output vent proximate the output reservoir.
- 30 17. The sensor cartridge of claim 8, wherein the housing comprises an air reservoir an opposing side of the surface acoustic wave sensor relative to the fluid path.

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- 18. The sensor cartridge of claim 8, wherein the electrical contacts of the circuit layer comprise circuit traces formed on the circuit layer.
- 19. A method of forming a surface acoustic wave assembly comprising electrically
 5 coupling a plurality of electrodes of a surface acoustic wave sensor to a plurality of electrical contacts of a circuit layer with a Z-axis conductive layer.
 - 20. The method of claim 19, further comprising providing an aperture in the circuit layer such that when the a plurality of electrodes are coupled to the plurality of electrical contacts of a circuit layer with a Z-axis conductive layer, the surface acoustic wave sensor is exposed via the aperture.
 - 21. The method of claim 19, wherein the Z-axis conductive layer comprises a Z-axis conductive elastomer.
 - 22. The method of claim 21, wherein the Z-axis conductive elastomer forms a hermetic barrier between the surface acoustic wave sensor and the circuit layer.
- 23. The method of claim 19, wherein the surface acoustic wave sensor comprises a
 Love mode shear-horizontal surface acoustic wave sensor.